



03560.003343

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Ryo KURODA et al.	: Examiner: John S. Ruggles
)
Application No.: 10/648,317	: Group Art Unit: 1756
)
Filed: August 27, 2003	:
)
	:
For: NEAR-FIELD PHOTOMASK, NEAR-FIELD) November 14, 2005
EXPOSURE APPARATUS USING THE	: (Monday)
PHOTOMASK, DOT PATTERN FORMING)
METHOD USING THE EXPOSURE APPARATUS,	:
AND DEVICE MANUFACTURED USING THE)
METHOD	:

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER SUBMITTING REPLACEMENT DRAWINGS

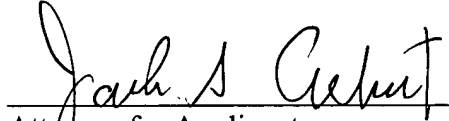
Sir:

Transmitted herewith are three (3) sheets of formal drawings to be substituted for the drawing sheets of Fig. 2, 3 and 4 presently on file in the above-identified application.

The new drawing sheets incorporates the changes requested by the Examiner in the Office Action mailed August 12, 2005.

Applicant's attorney, Steven E. Warner, may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.
below.

Respectfully submitted,

A handwritten signature in cursive script, reading "Jack S. Cubert", written over a horizontal line.

Attorney for Applicants
Jack S. Cubert
Registration No. 24,245

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3800
Facsimile: (212) 218-2200

DC_MAIN 222146v1



FIG. 2

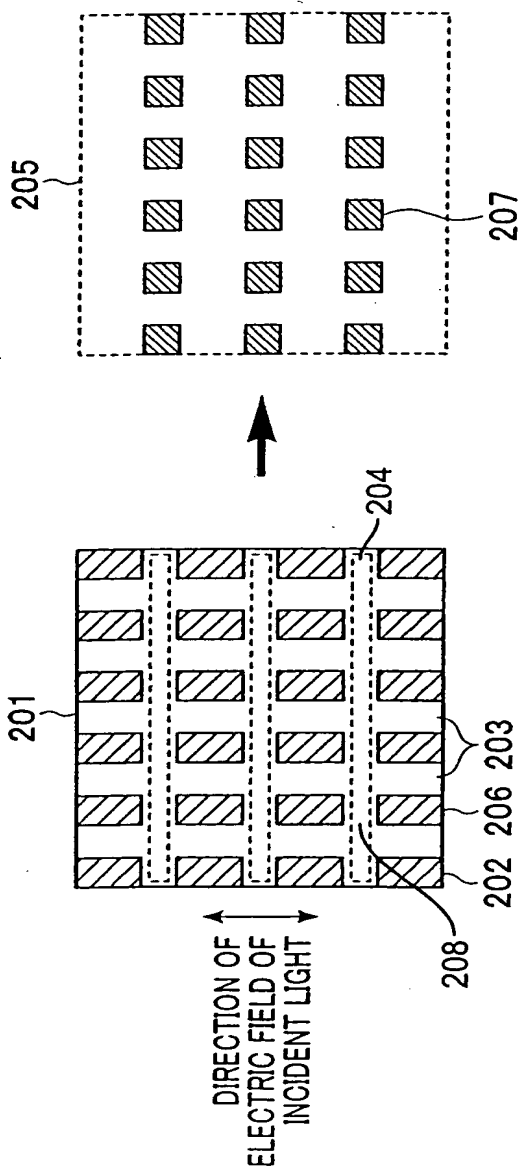
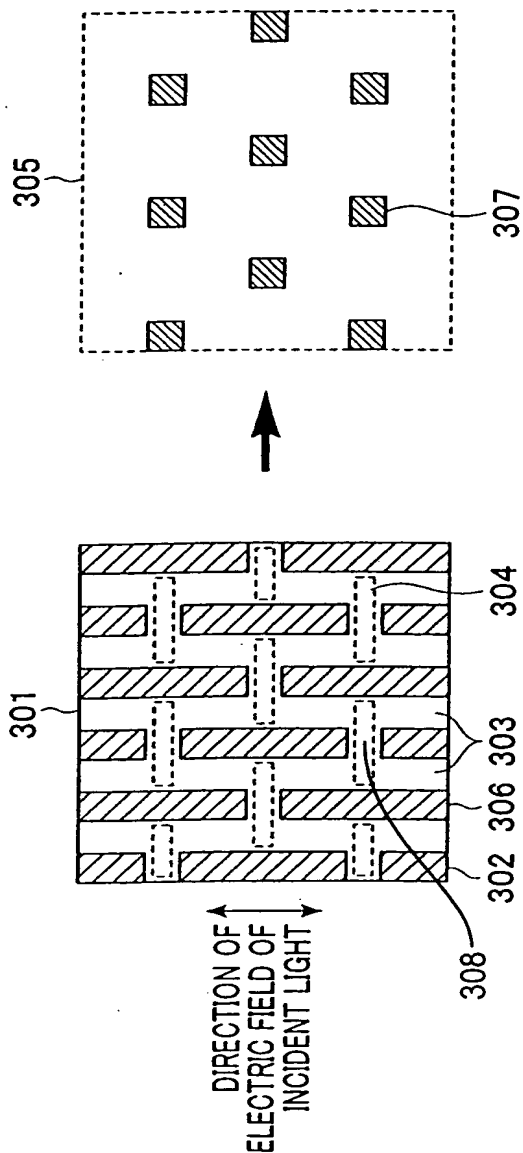


FIG. 3



4/13

FIG. 4

